



*image 7882*

Docket No. F-6971

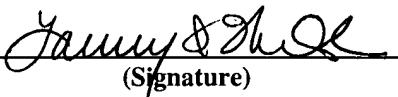
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Seiichi HAYASHI, et al.  
Serial No. : 09/852,111  
Filed : May 9, 2001  
For : METHOD AND APPARATUS FOR MEASURING THIN FILM, AND THIN FILM DEPOSITION SYSTEM  
Group Art Unit : 2882  
Examiner : Hoon K. Song  
Confirmation No. : 5010  
Customer No. : 000028107

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Lawrence I. Wechsler  
(Name)

  
(Signature)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

04/08/2004 WABRHAM1 00000110 101250 09852111  
01 FC:1253 950.00 DA

**INTRODUCTORY COMMENTS:**

Sir:

In response to the Office Action of October 3, 2003, please amend the above-identified patent application as follows: